

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Application Serial No. ....10/813,543  
Filing Date .....March 30, 2004  
Confirmation No. .... 8087  
Inventor.....F. Dan Gealy  
Assignee .....Micron Technology, Inc.  
Group Art Unit ..... 1792  
Examiner ..... Keath T. Chen  
Attorney's Docket No. .... MI22-3685  
Title:..... Method for Reducing Physisorption During Atomic Layer Deposition

**RESPONSE TO OCTOBER 8, 2008 ADVISORY ACTION TO ACCOMPANY  
A REQUEST FOR CONTINUED EXAMINATION (RCE)**

To:           Mail Stop RCE  
              Commissioner for Patents  
              P.O. Box 1450  
              Alexandria, VA 22313-1450

From:       Robert C. Hyta (Tel. 509-624-4276; Fax 509-838-3424)  
              Wells St. John P.S.  
              601 W. First Avenue, Suite 1300  
              Spokane, WA 99201-3828